Particle Characterization: Module 12, Lecture 39

1. Contrast CMP & mechanical polish.

2. What parameters does Preston's constant depend on?

3. In a dilute slurry, how does particle concentration affect removal rate?

4. Design a system to remove CMP residue from a polished surface.

5. Contrast Quick-Dump-Rinse (QDR) and Cascade Rinse (CR).

6. How do particles affect film deposition by PVD and CVD?

7. How do particles affect film deposition in a plasma reactor?

8. How do particles affect solar power generation?

9. How do particles affect aerospace components?

10. Define obscuration ratio.